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Docket No. F-6971

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Seiichi HAYASHI, et al.
Serial No. : 09/852,111
Filed : May 9, 2001
For : METHOD AND APPARATUS FOR MEASURING THIN FILM, AND THIN FILM DEPOSITION SYSTEM
Group Art Unit : 2882
Examiner : Hoon K. Song
Confirmation No. : 5010
Customer No. : 000028107

Certificate of Mailing Under 37 CFR 1.8

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(Signature)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

04/08/2004 WABRHAM1 00000110 101250 09852111
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INTRODUCTORY COMMENTS:

Sir:

In response to the Office Action of October 3, 2003, please amend the above-identified patent application as follows: